CLEAN SET OF CLAIMS

Serial No. 09/575,551

56. A method for processing a semiconductor wafer, data disk, semiconductor substrate and similar article requiring very low contaminant levels comprising the steps of:

moving a sealed container, holding at least one article in a horizontal orientation, [through] to an interface port of a processing system;

unsealing the container by removing a panel of the container, to provide access to the article in the container;

engaging the article with an engagement head;

pivoting the engagement head to move the article from a horizontal orientation into a vertical orientation;

releasing the article from the engagement head;

placing the article on a shelf with the article in a vertical orientation;

lifting the article off of the shelf with a transfer robot;

carrying the article on the robot to a process chamber;

opening the process chamber;

moving the article into the process chamber;

closing the process chamber;

processing the article in the process chamber.

57. The method of claim 56 where the interface port is part of a processing system within an enclosure.

62. The method of claim 56 wherein removing the panel of the container places the interior of the container in fluid communication with the workspace within the enclosure.

64. The freshod of claim 56 wherein the engagement head is pivoted upwardly to move the article from the horizontal to vertical orientation.

65. A method for processing a semiconductor wafer, data disk, semiconductor substrate and similar articles requiring very low contaminant levels, comprising the steps of:

moving a sealed container holding at least one article in a horizontal orientation, to an interface port of a processing system;

unsealing the container, to provide access to the article in the container;

engaging the article with an engagement head by moving the engagement head in a first direction;

pivoting the engagement head, to move the article from a horizontal orientation into a vertical orientation;

releasing the article from the engagement head and placing the article on a shelf with the article in a vertical orientation;

lifting the article off of the shelf with a transfer robot;

carrying the article on the transfer robot to a process chamber by moving the transfer

robot in a second direction, perpendicular to the first direction;

opening the process chamber;

placing the article into the process chamber;

closing the process chamber; and

processing the article in the process chamber.